



00839.000449

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: E. Kielin
ATSUSHI KOIKE ET AL.)
: Group Art Unit: 2813
Application No.: 09/982,846)
: Filed: October 22, 2001)
: For: METHOD FOR FORMING)
: A DEPOSITED FILM BY)
: PLASMA CHEMICAL VAPOR)
: DEPOSITION) March 19, 2003

#9/Amult
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3/27/03

Commissioner for Patents
Washington, D.C. 20231

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AMENDMENT

Sir:

a) Introductory Comments

This Amendment is filed in accordance with the OG Notice-1267 Off. Gaz
Pat. Office 106 of February 25, 2003 in which 37 C.F.R. §1.121(a)-(d) is waived for
amendments to the application where the Amendment complies with the Revised
Amendment Format of the OG Notice.

In response to the Office Action dated December 23, 2003, Applicants
respectfully request entry of the following amendments and comments into the file of the
above-identified application.